



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of: **Masayuki FURUHASHI et al.**

Group Art Unit: **2813**

Application Number: **10/696,775**

Examiner: **Stephen W. Smoot**

Filed: **October 30, 2003**

Confirmation Number: **7971**

For: **METHOD FOR FABRICATING A SEMICONDUCTOR DEVICE  
INCLUDING THE USE OF A COMPOUND CONTAINING  
SILICON AND NITROGEN TO FORM AN INSULATION FILM  
OF SiN, SiCN OR SiOCN**

Attorney Docket Number: **032076**  
Customer Number: **38834**

**PETITION FOR EXTENSION OF TIME**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

July 18, 2006

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated January 19, 2006 for three month(s) from April 19, 2006 to July 19, 2006.

Attached please find a check in the amount of \$1,020.00 for the cost of the extension.

If any additional fees are due in connection with this paper, please charge Deposit Account No. 50-2866.

Respectfully submitted,

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